

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of: KOSHELEV *et al.*

Confirmation No.: 3252

Application No.: 10/664,065

Examiner: Wells, Nikita

Filed: September 17, 2003

Group Art Unit: 2881

For: RADIATION SOURCE, LITHOGRAPHIC APPARATUS AND DEVICE MANUFACTURING
METHOD

COMMENTS ON EXAMINER'S STATEMENT OF REASONS FOR ALLOWANCE

Mail Stop Issue Fee
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicant confirms with appreciation the receipt of the Notice of Allowability for the above-identified application.

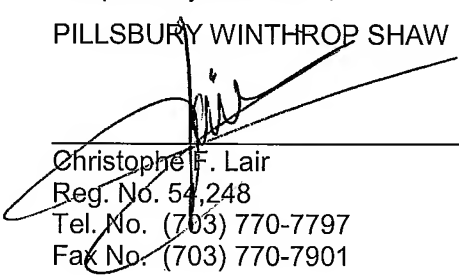
In reply to the Examiner's reasons for allowance in this application, Applicant respectfully submits that the subject matter of the allowed claims is patentable for their respective recitations of claimed features as a whole, without any particular criticality or distinguishing feature being attributable to any one or more of such features, and without any narrowing interpretation being imposed on any of such features. As such, Applicant respectfully submits that no one element or limitation in particular should be deemed to impart to or be required for patentability of the claims. Applicant also submits that the dependent claims are allowable for their dependence on the allowed independent claims and further for the additional subject matter recited in each of those dependent claims.

These comments are being filed concurrently with the Issue Fee. Please charge any fees, if any, associated with the submission of this paper to Deposit Account Number 033975 (Ref. No. 081468-0306001). The Commissioner for Patents is also authorized to credit any over payments to the above-referenced Deposit Account.

Respectfully submitted,

PILLSBURY WINTHROP SHAW PITTMAN LLP

Date: March 24, 2009



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